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APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
DEPARTMENT		

Fig. 1

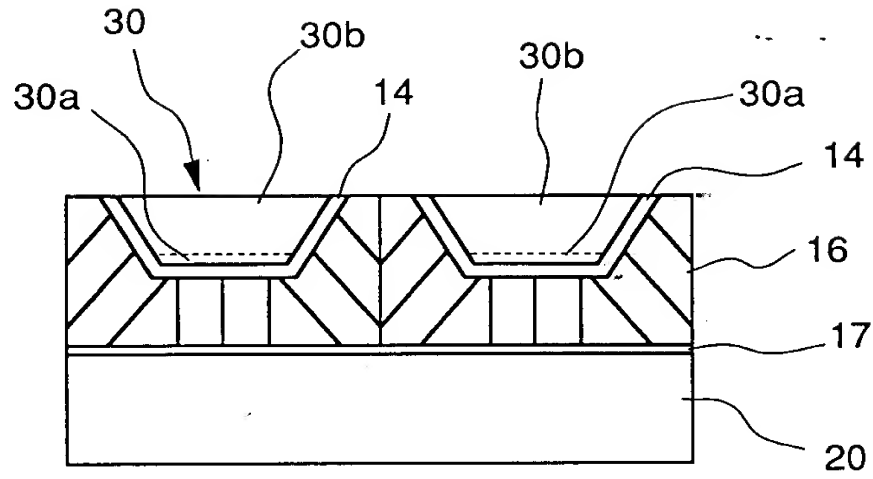
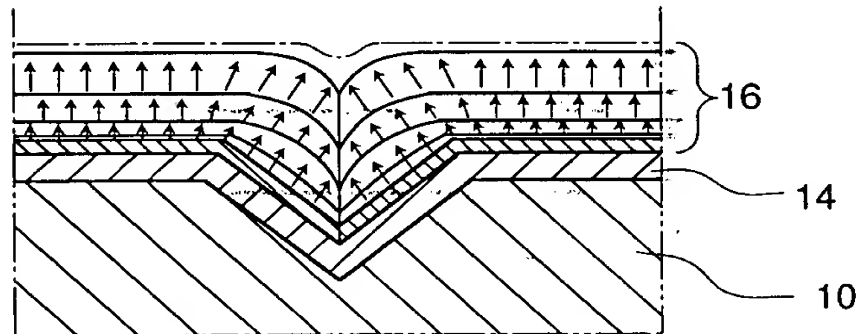


Fig. 6



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
FILE		

Fig. 2A



Fig. 2B

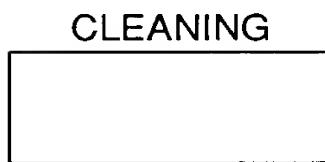


Fig. 2C

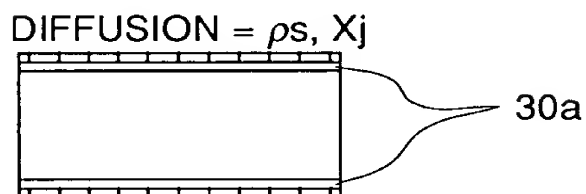


Fig. 2D

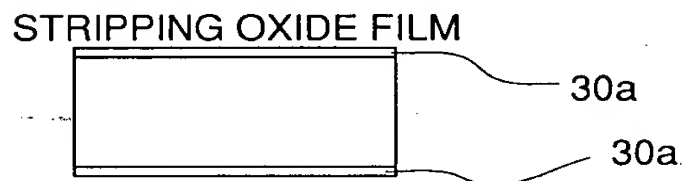


Fig. 2E

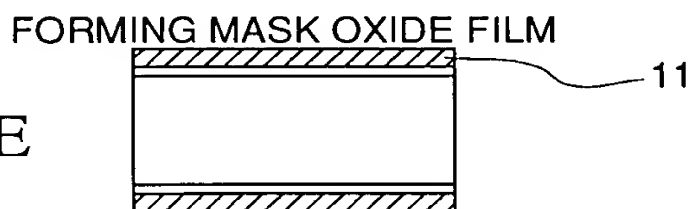
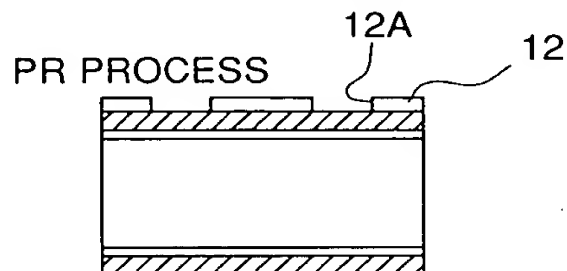


Fig. 2F



APPROVED	O.G. FIG.	
BY	CLASS	SUBCLASS
CRAFTSMAN		

Fig. 3A

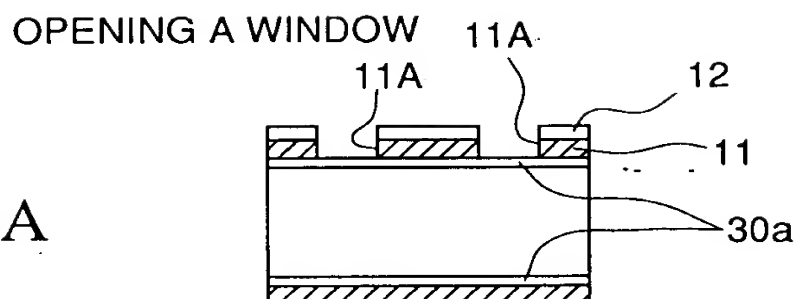


Fig. 3B

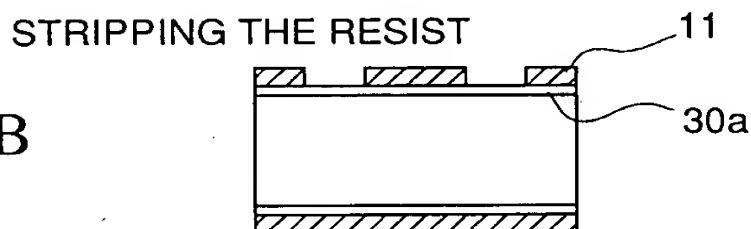


Fig. 3C

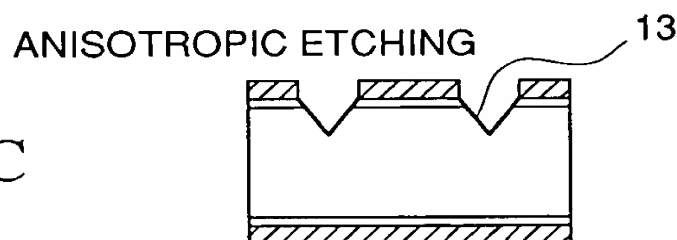


Fig. 3D

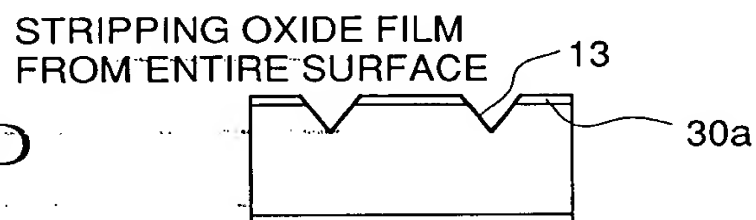


Fig. 3E

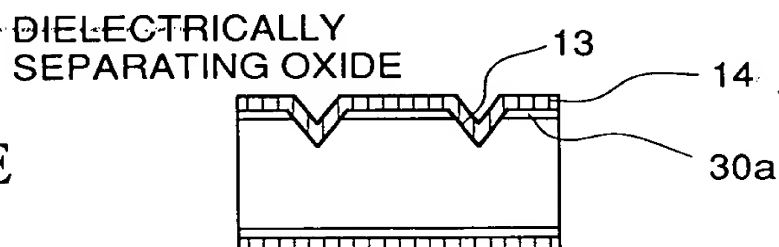
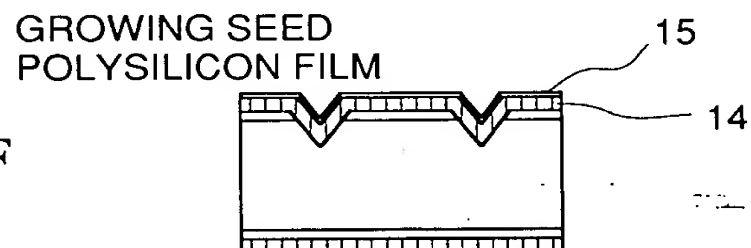
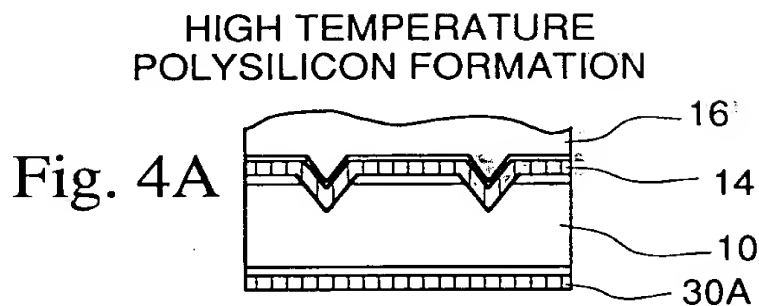
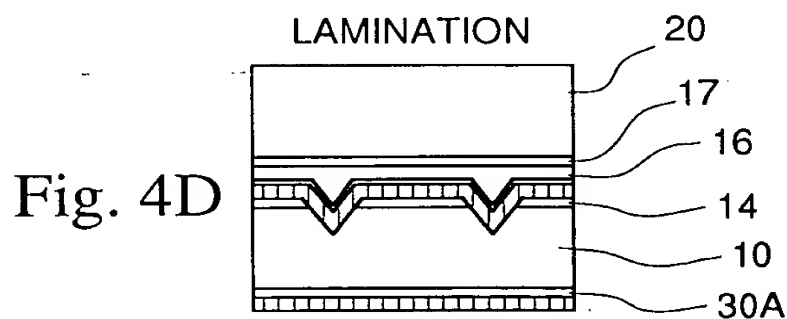
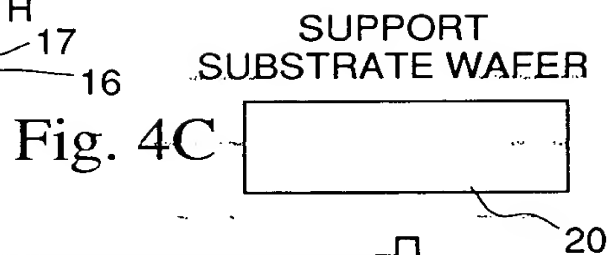
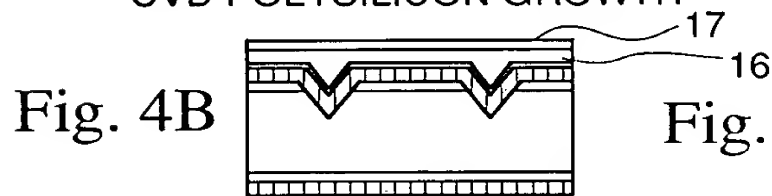


Fig. 3F

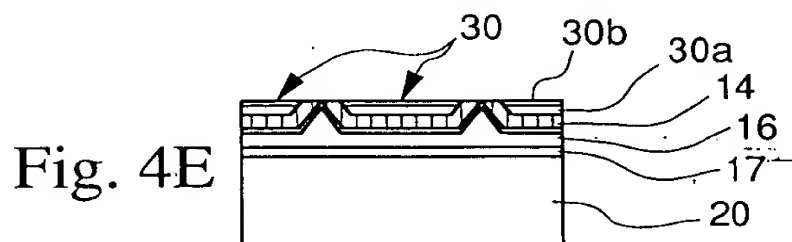




HIGH TEMPERATURE CVD
POLYSILICON GRINDING AND
POLISHING POLISHING
AFTER LOW TEMPERATURE
CVD POLYSILICON GROWTH



CHAMFERING PERIPHERY SEPARATION
GRINDING AND POLISHING



APPROVED	O.G.	FIG.
BY	CLASS	SUBCLASS
DRAFTSMAN		

Fig. 5A

P-TYPE OR N-TYPE(100)



Fig. 5B

THROUGH OXIDE
FILM FORMATION

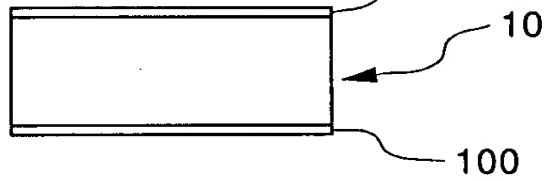


Fig. 5C

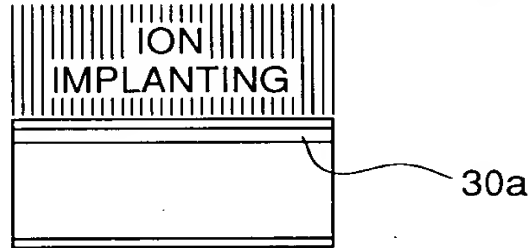


Fig. 5D

STRIPPING THE OXIDE FILM
FROM THE WHOLE SURFACE

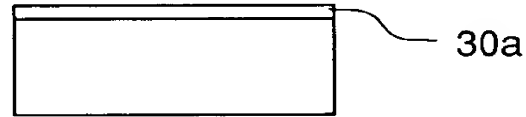


Fig. 5E

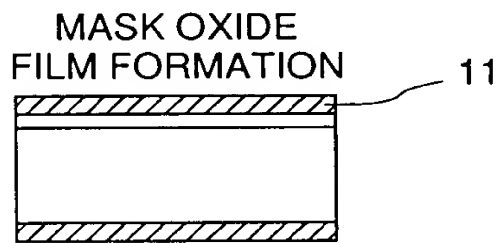
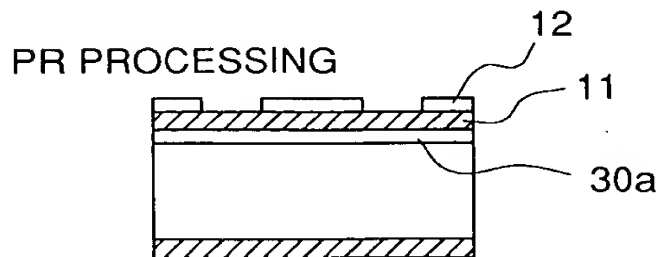


Fig. 5F



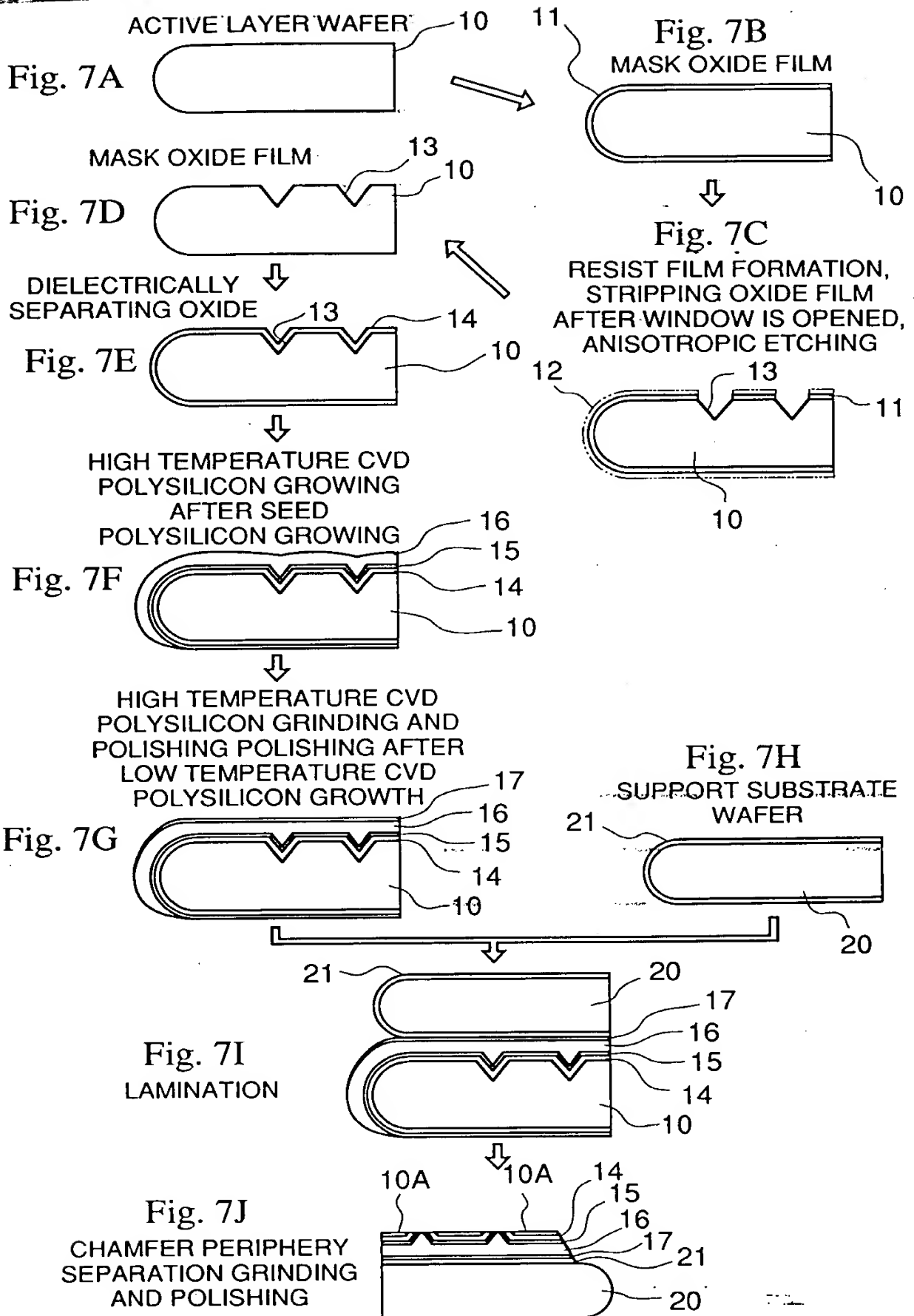


Fig. 8

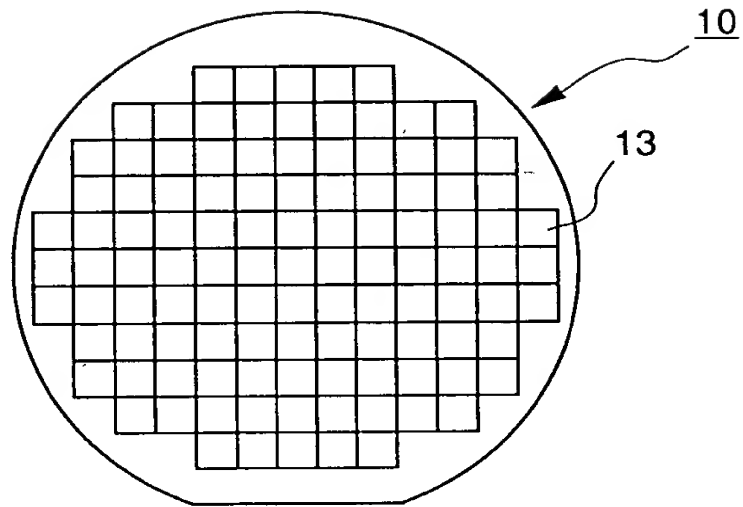
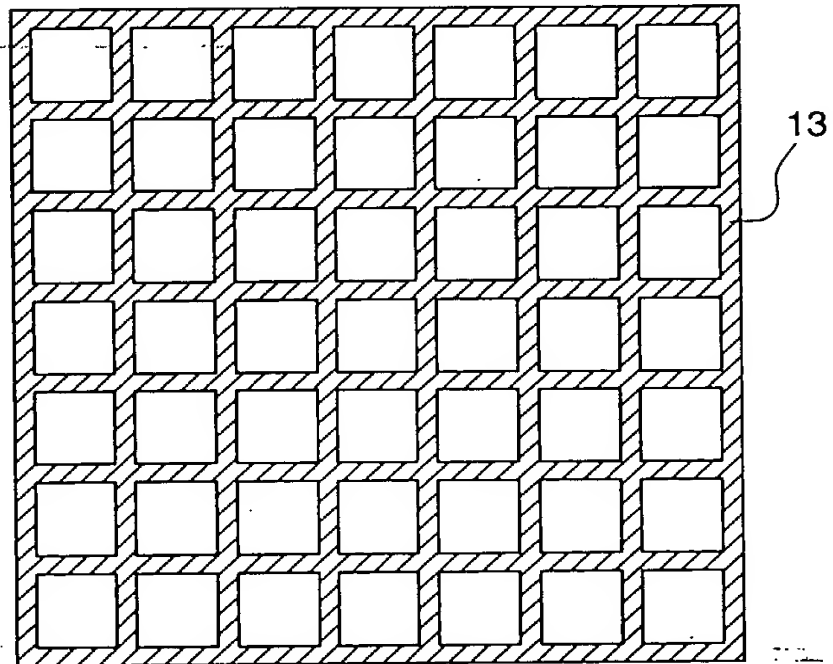


Fig. 9



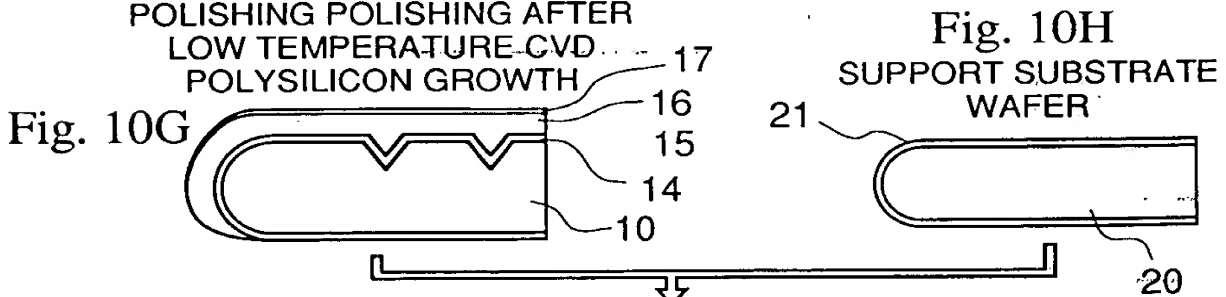
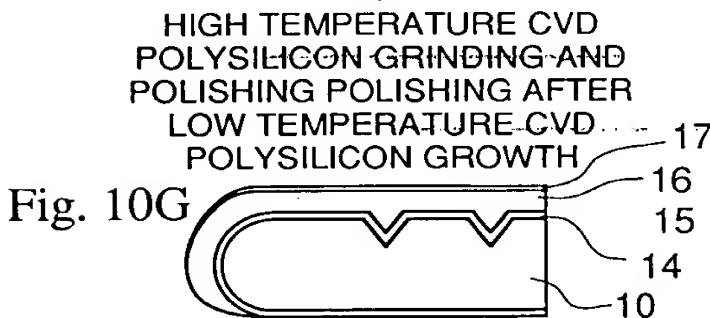
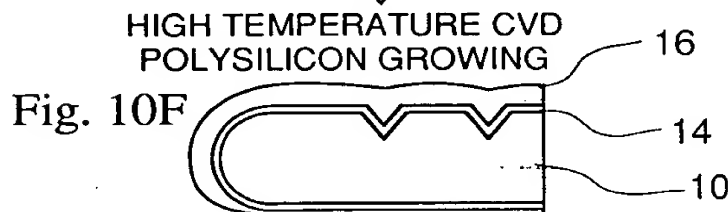
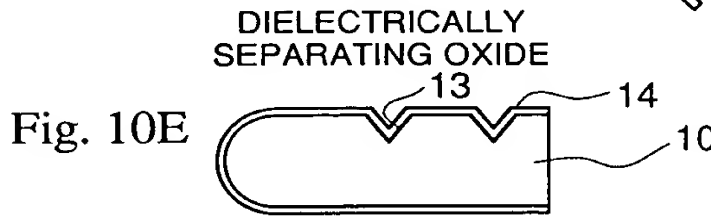
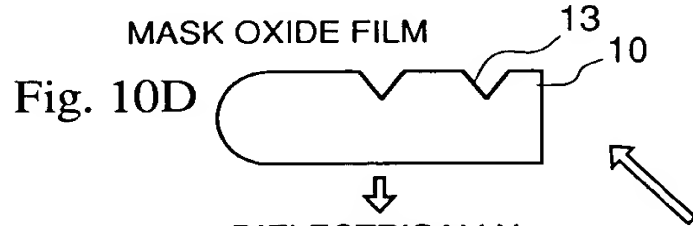
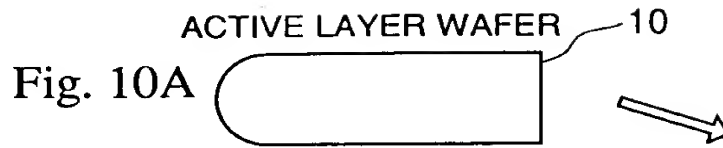


Fig. 10I
LAMINATION

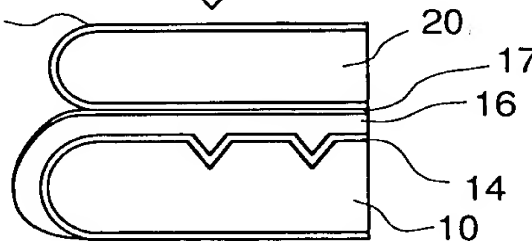


Fig. 10J
CHAMFER PERIPHERY SEPARATION GRINDING AND POLISHING

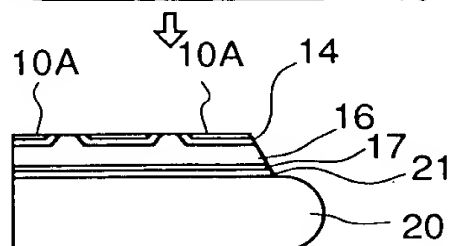


Fig. 10B

MASK OXIDE FILM

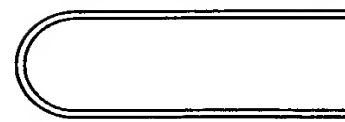


Fig. 10C

RESIST FILM FORMATION,
STRIPPING OXIDE FILM
AFTER WINDOW IS OPENED,
ANISOTROPIC ETCHING

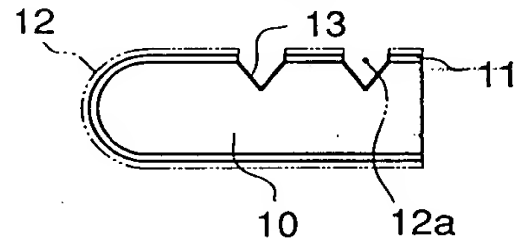


Fig. 11

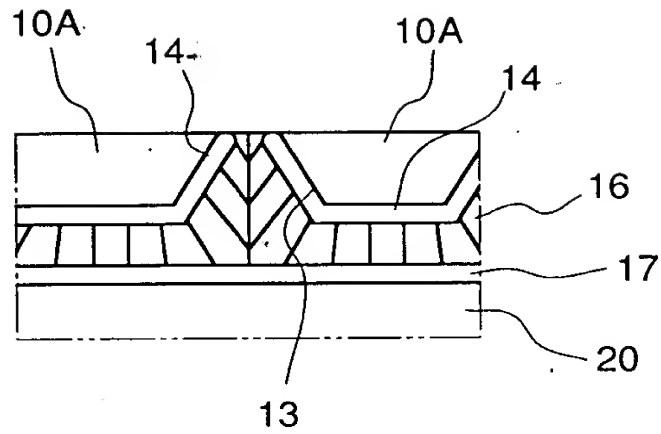


Fig. 12

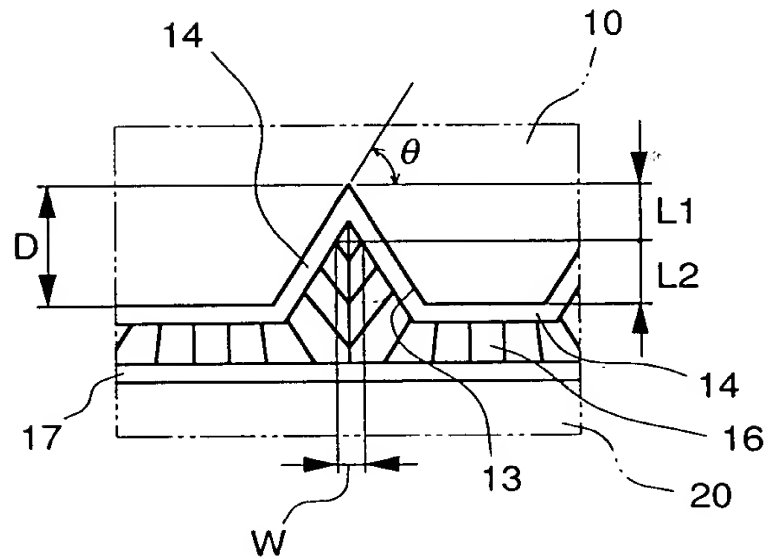


Fig. 13

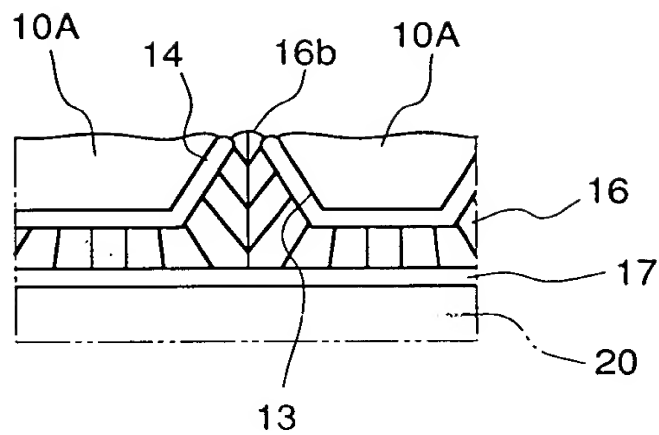
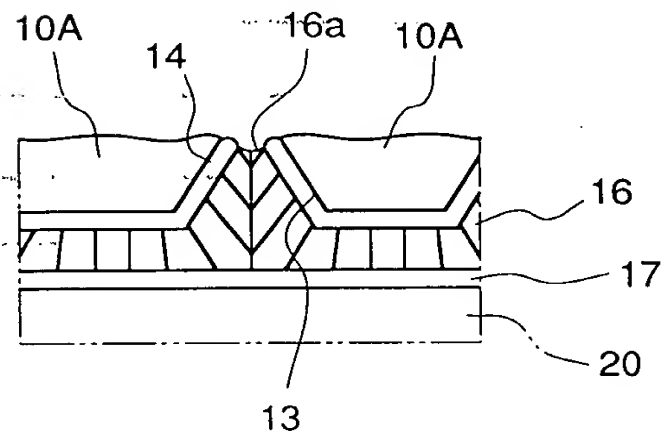


Fig. 14



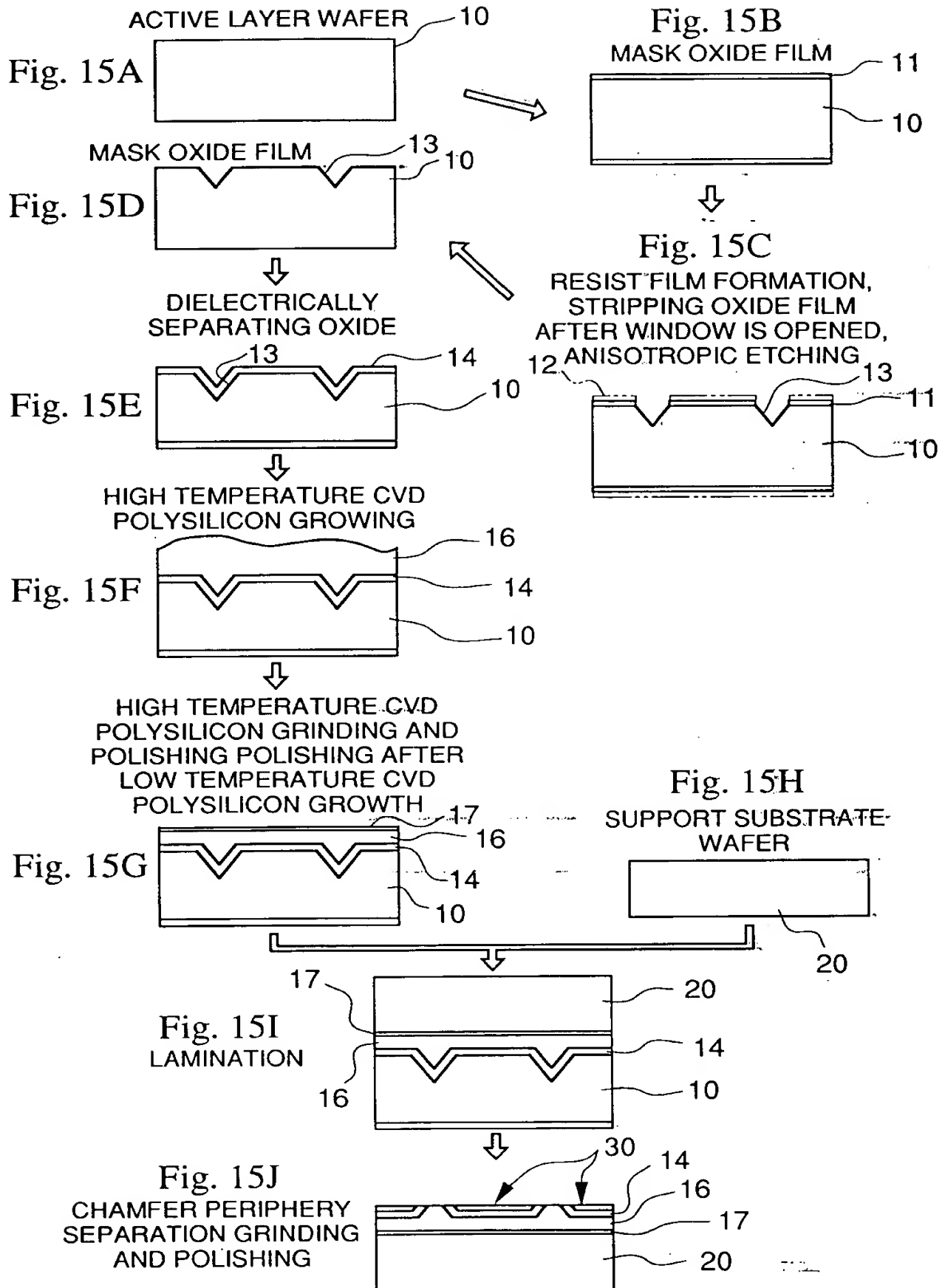


Fig. 16

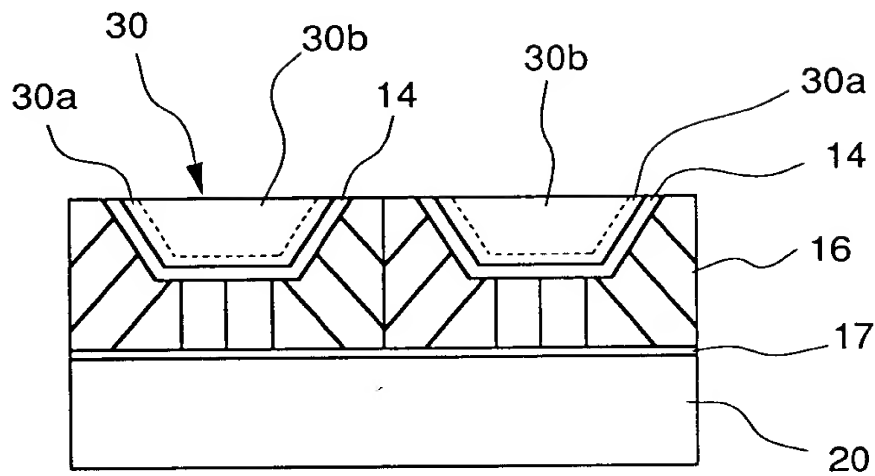


Fig. 17

